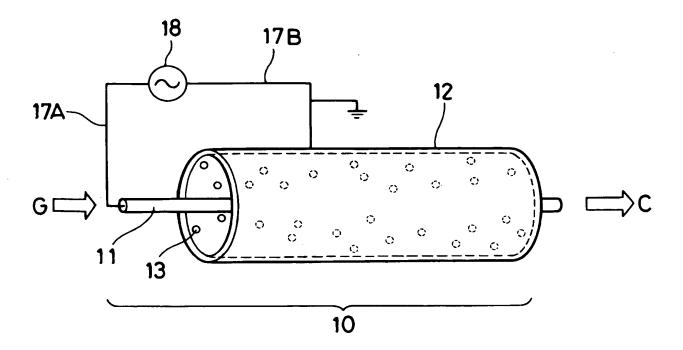
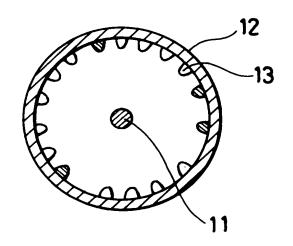
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FIG. 1



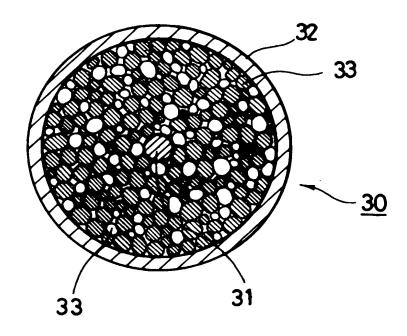
F I G. 2



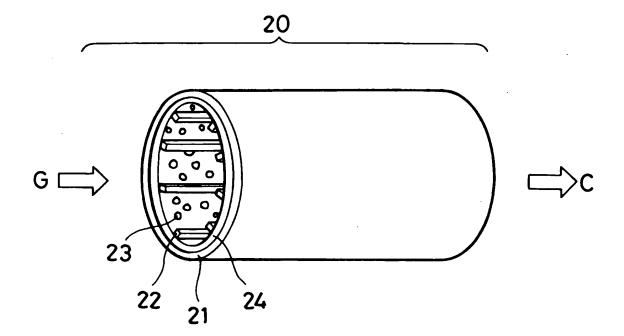
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FIG. 3



F I G. 4



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FIG. 5

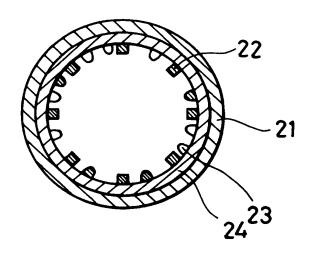
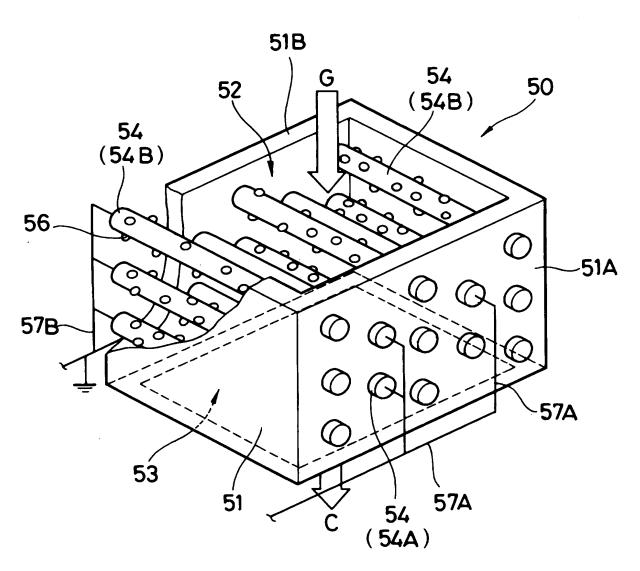
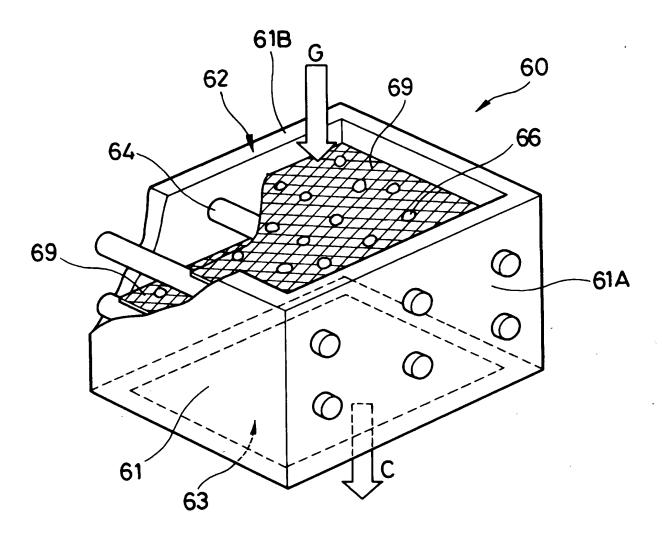


FIG. 6



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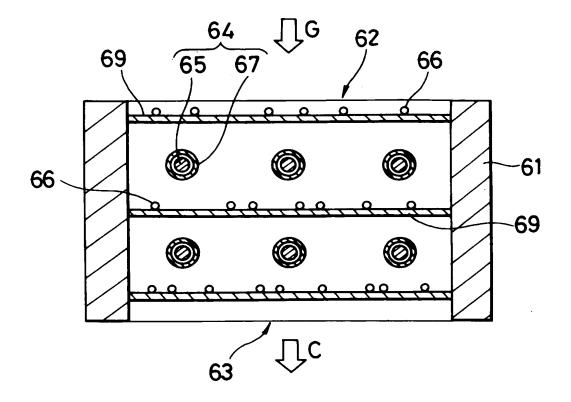
F I G. 7



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FIG. 8



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F I G. 9

